REC'D	28	FEB	2005
WIPO			PCT

PCT

INTERNATIONAL PRELIMINARY EXAMINATION REPORT

(PCT Article 36 and Rule 70)

Applicant's or agent's file reference 03 GI 24 E FOR FURTHER ACTION See Notification of Transmittal of International Preliminary Examination Report (Form PCT/IPEA/416)					
International application No. PCT/IT 03/00363	International filing date (day/mon. 11.06.2003	th/year) Priority date (day/month/year) 10.12.2002			
International Patent Classification (IPC) or both national classification and IPC C23C16/46					
Applicant E.T.C. EPITAXIAL TECHNOLOGY	CENTER S.R.L. et al.				
This international preliminary examination report has been prepared by this International Preliminary Examining Authority and is transmitted to the applicant according to Article 36.					
2. This REPORT consists of a total	of 6 sheets, including this cove	r sheet.			
been amended and are the	This report is also accompanied by ANNEXES, i.e. sheets of the description, claims and/or drawings which have been amended and are the basis for this report and/or sheets containing rectifications made before this Authority (see Rule 70.16 and Section 607 of the Administrative Instructions under the PCT).				
These annexes consist of a total	These annexes consist of a total of 4 sheets.				
This report contains indications report.	elating to the following items:				
I ⊠ Basis of the opinion					
II □ Priority					
_	opinion with regard to novelty, i	nventive step and industrial applicability			
IV Lack of unity of inven		The second secon			
V 🗵 Reasoned statement citations and explana	under Rule 66.2(a)(ii) with rega tions supporting such statement	rd to novelty, inventive step or industrial applicability;			
VI ☐ Certain documents ci					
VII ☐ Certain defects in the	international application				
VIII Certain observations	on the international application				
		formulation of this round			
Date of submission of the demand Date of completion of this report		т сотриниот от иль тероп			
11.05.2004		2.2005			
Name and mailing address of the internatio preliminary examining authority:	nal Author	ized Officer			
European Patent Office D-80298 Munich Tel. +49 89 2399 - 0 Tx: 523	656 epmu d	eau, P-O			
	. i elepr	10110 140. T-40 00 2000-0-10 1			

INTERNATIONAL PRELIMINARY EXAMINATION REPORT

International application No.

PCT/IT 03/00363

I. Basis	of the	report
----------	--------	--------

1. With regard to the **elements** of the international application (Replacement sheets which have been furnished to the receiving Office in response to an invitation under Article 14 are referred to in this report as "originally filed" and are not annexed to this report since they do not contain amendments (Rules 70.16 and 70.17)):

	De	scription, Pages		
	1-1	2	as or	iginally filed
	Cla	ims, Numbers		
	2-1	-	recei	ved on 11.05.2004 with letter of 10.05.2004
	1			ved on 20.12.2004 with letter of 20.12.2004
	•		1000.	100 011 20.12.12004 With lotter of 20.12.2004
	Dra	wings, Sheets		
	1-5		as or	iginally filed
2.	Wit lan	h regard to the lang u guage in which the in	iage, all the eleternational app	ements marked above were available or furnished to this Authority in the Dication was filed, unless otherwise indicated under this item.
	The	ese elements were av	ailable or furn	ished to this Authority in the following language: , which is:
		the language of a tra	anslation furnis	shed for the purposes of the international search (under Rule 23.1(b)).
				international application (under Rule 48.3(b)).
		the language of a tra Rule 55.2 and/or 55.	anslation furnis .3).	shed for the purposes of international preliminary examination (under
3.	Wit inte	h regard to any nucle rnational preliminary	e otide and/or a examination w	amino acid sequence disclosed in the international application, the vas carried out on the basis of the sequence listing:
		contained in the inte	ernational appli	cation in written form.
		filed together with th	ne international	application in computer readable form.
		furnished subseque	ntly to this Aut	hority in written form.
		furnished subseque	ntly to this Aut	hority in computer readable form.
		The statement that to in the international a	the subsequen application as f	tly furnished written sequence listing does not go beyond the disclosure iled has been furnished.
		The statement that the listing has been furn	the information ished.	recorded in computer readable form is identical to the written sequence
1.	The	amendments have r	esulted in the	cancellation of:
		the description,	pages:	
		the claims,	Nos.:	20
		the drawings,	sheets:	

INTERNATIONAL PRELIMINARY **EXAMINATION REPORT**

International application No.

PCT/IT 03/00363

5. 🗆	This report has been established as if (some of) the amendments had not been made, since they have
	been considered to go beyond the disclosure as filed (Rule 70.2(c)).

(Any replacement sheet containing such amendments must be referred to under item 1 and annexed to this

- 6. Additional observations, if necessary:
- V. Reasoned statement under Article 35(2) with regard to novelty, inventive step or industrial applicability; citations and explanations supporting such statement
- 1. Statement

Novelty (N)

No:

Yes: Claims Claims 1-19

Inventive step (IS)

Yes: Claims

No: Claims

1-19

Industrial applicability (IA)

Yes: Claims

1-19

No: Claims

2. Citations and explanations

see separate sheet

Re Item V

Reasoned statement with regard to novelty, inventive step or industrial applicability; citations and explanations supporting such statement

1). Reference is made to the following documents:

D1: US 2002/090454 A1 (Kordina Olle et al) 11 July 2002 (2002-07-11)

D2: US-A-5 221 356 (Becker Jurgen et al) 22 June 1993 (1993-06-22)

2). The present application does not meet the criteria of Article 33(1) PCT, because the subject-matter of claims 1-19 does not involve an inventive step in the sense of Article 33(3) PCT.

2.1). Document D1 is regarded as being the closest prior art to the subject-matter of claim 1 and discloses (see Figures 1, 6, 7, 9, 10 and 12-14; page 2, paragraph 31 to page 4, paragraph 47; page 4, paragraphs 55-57) a system comprising a stationary base element (150) and a movable support (130) for at least one substrate (20), the support (130) being rotatable above the base element (150) about a stationary axis (133,163), a chamber (160) being defined between said element (150) and said support (130), whereas one duct (170) is provided for the admission of at least one gas flow to said chamber in order to raise said support (130) with an outlet opening (174) into the chamber in such a manner that the emerging gas-flow is parallel to the axis of rotation of the support (130).

The subject-matter of claim 1 therefore differs from this known system in that said outlet opening is configured in such a manner that the emerging gas-flow is skew with respect to said axis of rotation.

The subject-matter of claim 1 is therefore new (Article 33(2) PCT).

2.2). The problem to be solved by the present invention may be regarded as using said flow of gas emerging from said outlet opening (174) not only to raise said support (130) but also to rotate it.

The solution to this problem proposed in claim 1 of the present application cannot be

International application No. PCT/IT 03/00363

considered as involving an inventive step (Article 33(3) PCT) for the following reasons.

This feature, i.e. using a skewed emerging gas flow for putting into rotation the substrate, has already been employed for the same purpose in a similar system, as can be seen from document D2 (see figures 4 and 6; column 6, lines 1-19).

Since the problem of raising a heavy graphite support capable of carrying several wafers by means of a gas flow has already been solved satisfactorily in document D1 as in the present application by means of a chamber (160) under said support (130), the skilled person would not be prevented to take into consideration the teachings of document D2, even if document D2 only describes the raising and rotating of a single wafer, i.e. of a lighter "substrate assembly" than one capable of carrying several wafers.

It would therefore be obvious to the skilled person, namely when the same result is to be achieved, i.e. rotating an already floating "substrate assembly", to apply this feature, i.e a skewed emerging gas flow, with corresponding effect to a system according to document D1, thereby arriving at a system according to claim 1.

- 2.4). Dependent claims 2 to 17 do not contain any additional features which, in combination with the features of claim 1 to which they refer, meet the requirements of the PCT in respect of inventive step. In fact, said claims are related to features which, either are known or suggested from documents D1 and/or D2, or are usual in this technical field, or may be carried out by the specialist with his common knowledge without any inventive effort
- 2.5). Since document D1, respectively D2, describes the use of the above-mentioned system in a reactor for epitaxial growth of semiconductor materials (cf document D1, col.1, paragraphs 1-3), respectively in an apparatus for the thermal treatment of wafers (cf document D2, col.2, lines 29-34), the same reasoning applies, mutatis mutandis, to the subject-matter of the corresponding independent claims 18 and 19, which therefore are also considered not inventive.



International application No. PCT/IT 03/00363